

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: :

Christine Hau-Riege, et al. : Group Art Unit: Not yet assigned

Serial No.: 60/501,445 : Examiner: Not yet assigned

Filed: September 9, 2003 :

Title: SEMICONDUCTOR COMPONENT AND METHOD FOR PRECLUDING STRESS-INDUCED VOID INFORMATION IN THE SEMICONDUCTOR COMPONENT

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached hereto is a completed Form PTO-1449 listing patents, publications, or other information which the applicant believes may be material to the examination of this application, with copies of each such item enclosed herewith. It is requested that the cited patents be made of record in the examination of this application. This information disclosure statement is being filed prior to the first Office Action and no certification or fee is required. The commissioner is authorized to charge any fee deficiency required by this paper or credit any overpayment to Deposit Account No. 50-2173. A duplicate of this communication is enclosed.

Respectfully submitted,

By _____

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Dated: 29 Oct 2003

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	ATTY. DOCKET NO. H1508	SERIAL NO Not yet assigned
	APPLICANT Christine Hau-Riege, et al.	
	FILING DATE Herewith	GROUP

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES NO

OTHER DOCUMENTS (Including Author, Title, Date Pertinent Pages, Etc.)

Ogawa, E.T., et al., Stress-Induced Voiding Under Vias Connected To Wide Cu Metal Leads,

EXAMINER _____ **DATE
CONSIDERED** _____

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.